

MSI-1

JC974 U.S. PRO
09/776009
02/02/01



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Michael A. Vyvoda et al.

For : WAFER SURFACE THAT FACILITATES
PARTICLE REMOVAL

Serial No. : To Be Assigned

Hon. Assistant Commissioner
for Patents
Washington, D.C. 20231

#5105
D Wilson
1-13-02

INFORMATION DISCLOSURE STATEMENT

Sir:

In accordance with 37 C.F.R. §§ 1.56, 1.97, and 1.98, applicants wish to call the attention of the Examiner to the following documents:

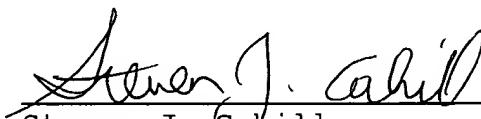
U.S. Patents

Johnson et al.	6,034,882	03/2000
Zhang	5,835,396	11/1998

These documents are listed on the accompanying Form PTO-1449 (submitted in duplicate) and copies are enclosed herewith.

Consideration of the foregoing in relation to this patent application is respectfully requested.

Respectfully submitted,



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